



Georgia Tech
Institute for Matter
and Systems

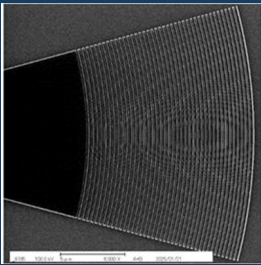
E-BEAM LITHOGRAPHY (EBL) SHORT COURSE

Advanced Nanoscale Patterning

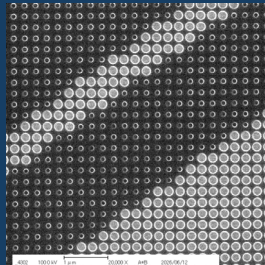
Oct 20-21, 2026

Marcus Nanotechnology Building
Rooms 1116-1118

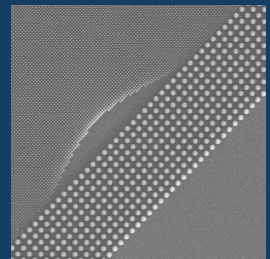
- Lectures by Georgia Tech IMS Experts
- Guest Lectures by Leading Nanofabrication Experts
- Advanced Electron Beam Lithography Techniques
- In lab cleanroom experience - Elionix ELS-G100
- Nanoscale Patterning & Device Fabrication
- Certificate of Completion



Waveguides



Metalens



Photonic Crystals

**Space is limited.
Register today!**



Georgia Tech Rate: \$200
Academic & Govt Rate: \$400
Industry Rate: \$1,000

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